

## Electronic Patent Application Fee Transmittal

<b>Application Number:</b>	09991196			
<b>Filing Date:</b>	20-Nov-2001			
<b>Title of Invention:</b>	HIGH DENSITY PLASMA CHEMICAL VAPOR DEPOSITION PROCESS			
<b>First Named Inventor:</b>	Chih-Chien Liu			
<b>Filer:</b>	Peter John Meza/Julie Lange			
<b>Attorney Docket Number:</b>	UMC-96-279 CON2			
Filed as Large Entity				
<b>Utility      Filing Fees</b>				
<b>Description</b>	<b>Fee Code</b>	<b>Quantity</b>	<b>Amount</b>	<b>Sub-Total in USD(\$)</b>
<b>Basic Filing:</b>				
<b>Pages:</b>				
<b>Claims:</b>				
<b>Miscellaneous-Filing:</b>				
<b>Petition:</b>				
<b>Patent-Appeals-and-Interference:</b>				
Notice of appeal	1401	1	500	500
Post-Allowance-and-Post-Issuance:				
<b>Extension-of-Time:</b>				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Total in USD (\$)				500